

# High accuracy assessment of the spatial frequency constancy of the grating scale of a displacement sensor



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# OUTLINE

- **Gratings made by Step & Repeat : Problems**
  - **A very sensitive measurement technique: 1 pm on the period**
  - **The stitching errors**
  - **The lens system aberrations**
  - **Conclusion**
-

# Grating manufacturing by microelectronic technologies

## Interests

- Submicron period
- Long length (300 mm), large size
- High productivity
- High reproducibility
- Open, standard processes

## Problems

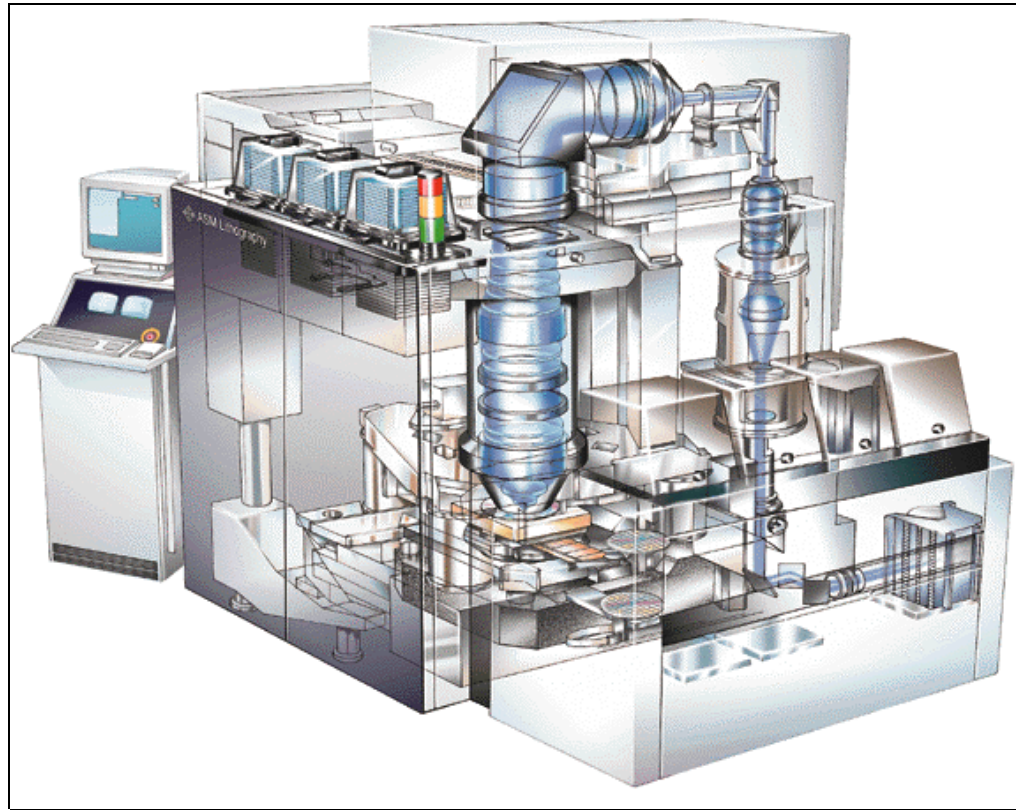
All concentrated in the Step & Repeat camera

- Stitching errors
- Field distortion

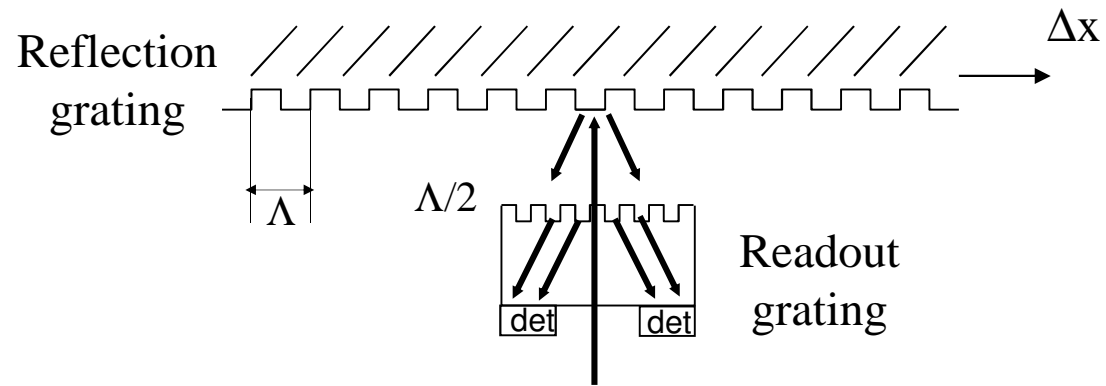
## Assessment of a ASML PAS 5500

- I-Line (365 nm)
  - Wafer scale 1 $\mu$ m period grating
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# ASML Stepper PAS 5500



## Very sensitive characterization of grating spatial frequency

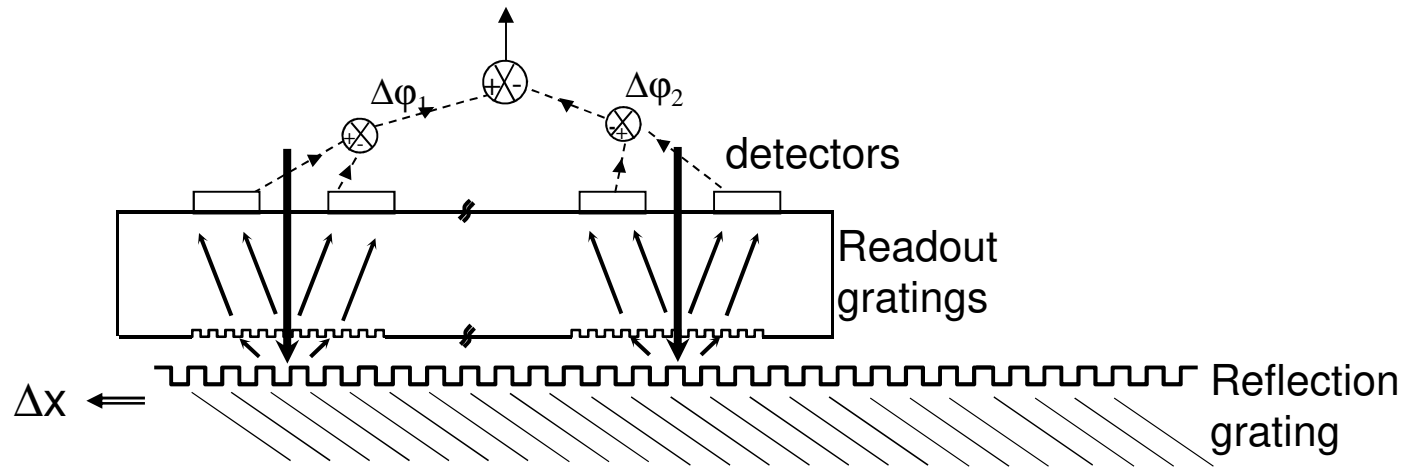


$$\Delta\phi = 2 K_g(x) \Delta x$$

$$K_g(x) = 2\pi/\Lambda(x)$$

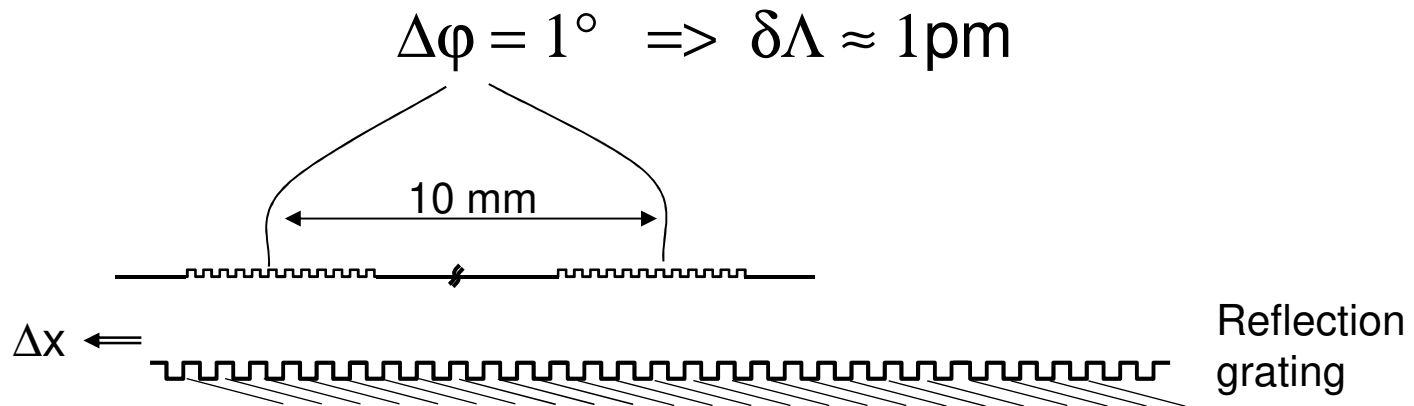
- **Diffraction interferometric scheme**
  - **Counts the number of periods over displacement  $\Delta X$**
  - **Nanometric resolution**
-

## Two such sensors...

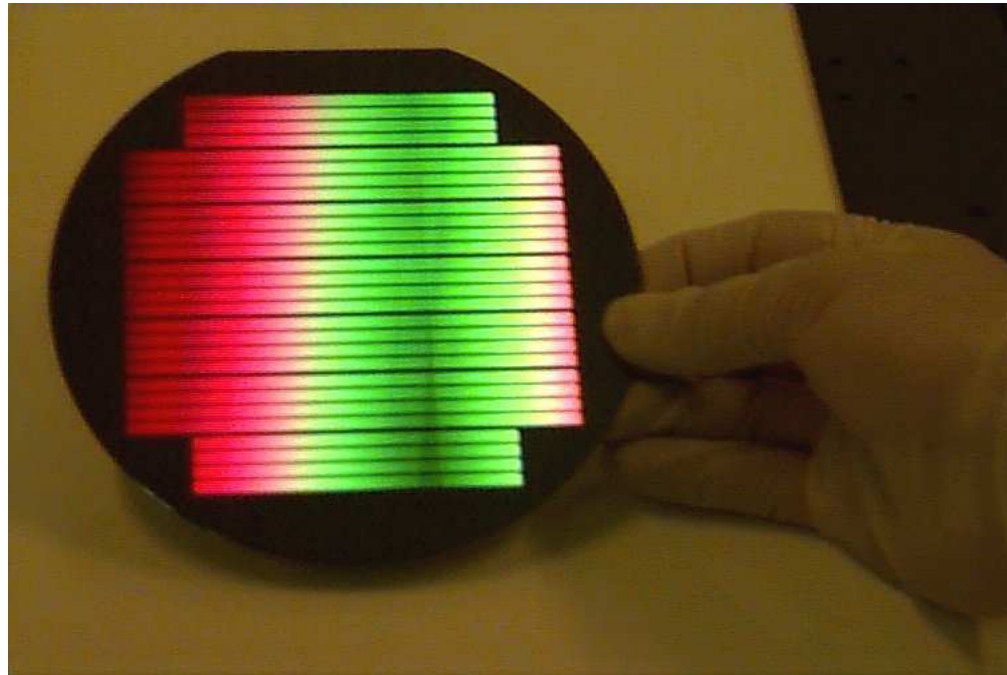


$$\frac{d}{dx}(\Delta\phi_1 - \Delta\phi_2) = K_g(x+L) - K_g(x)$$

...measure the variation of the grating spatial frequency



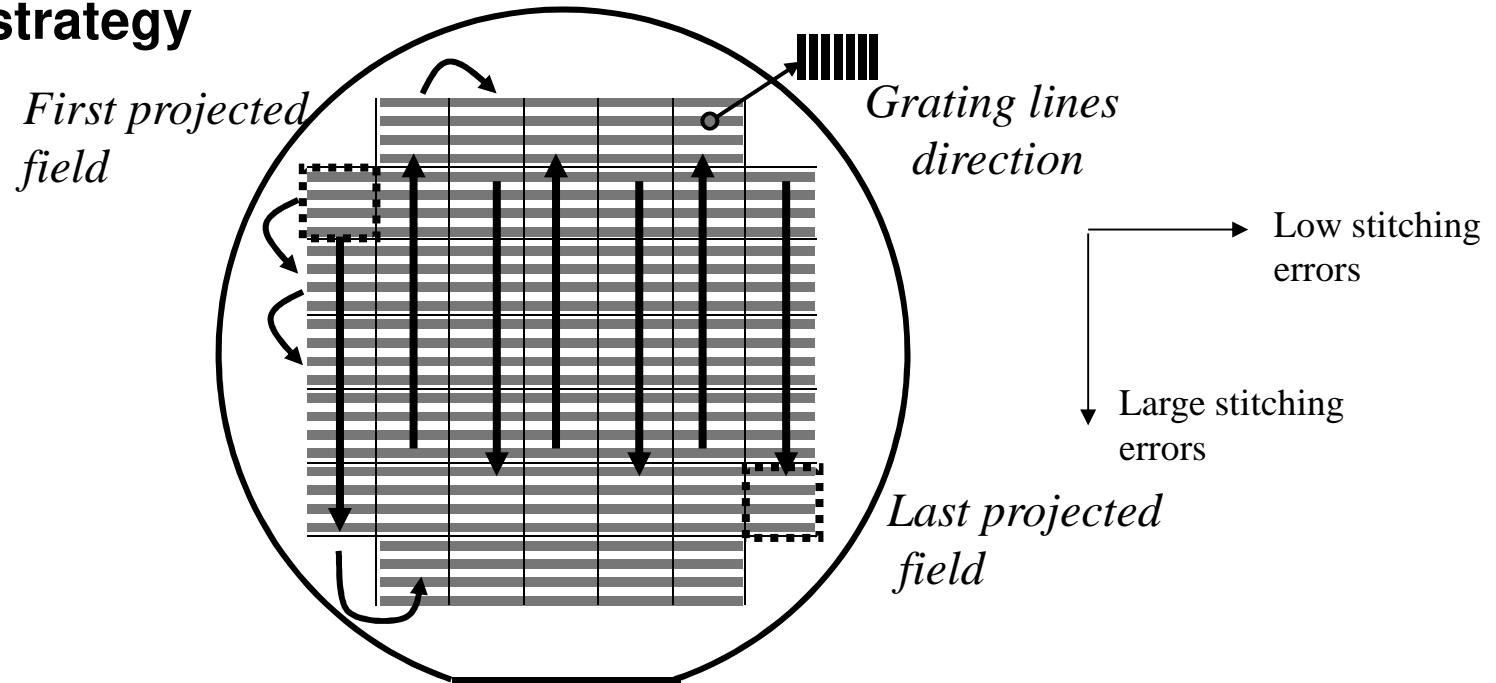
## Grating wafer



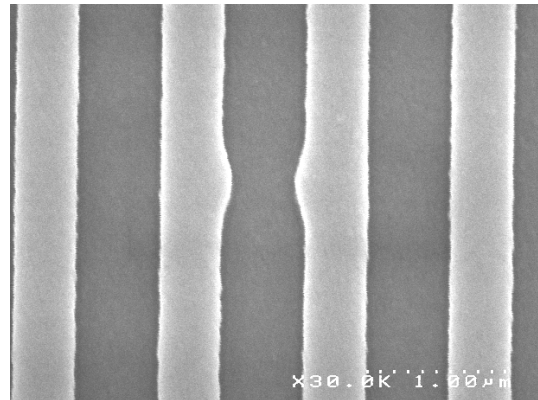
- 6 inches
  - $\Lambda = 1 \mu\text{m}$
  - Stepped, etched, metal coated
  - Field size 16x16 mm
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# Stitching errors

- **Printing strategy**



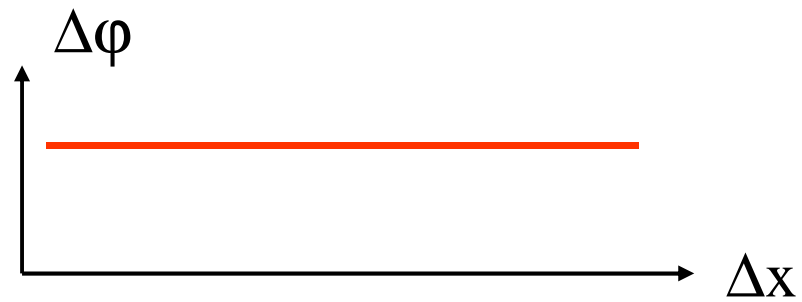
- **Matrice-tenon joint**  
**< 10 nm error**



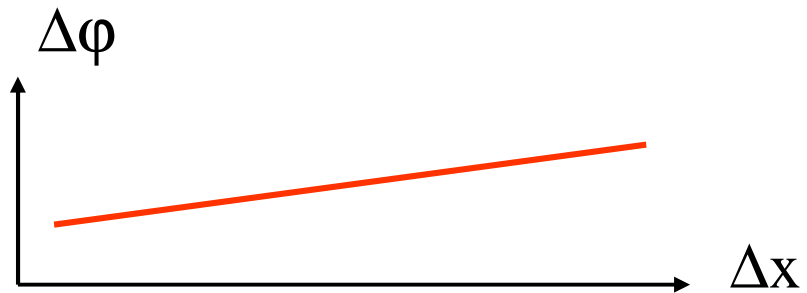


## Field distortion

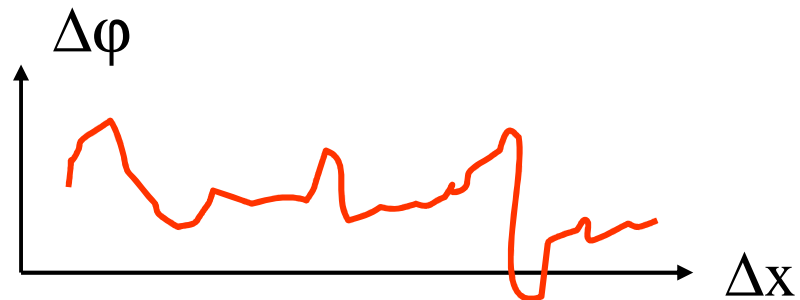
- Constant period grating



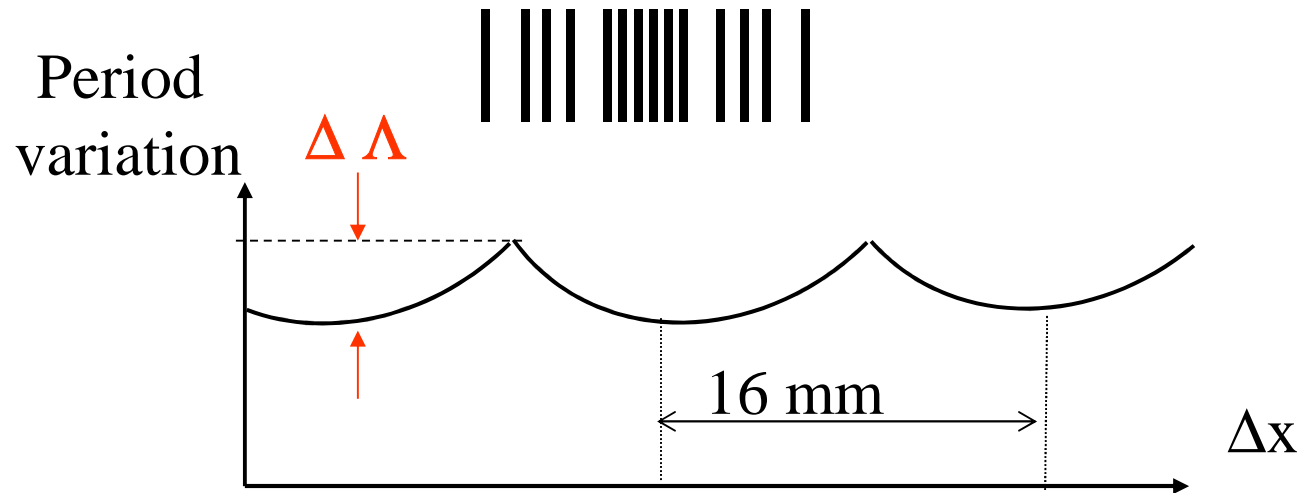
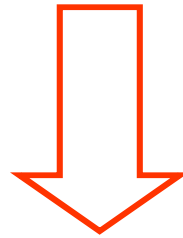
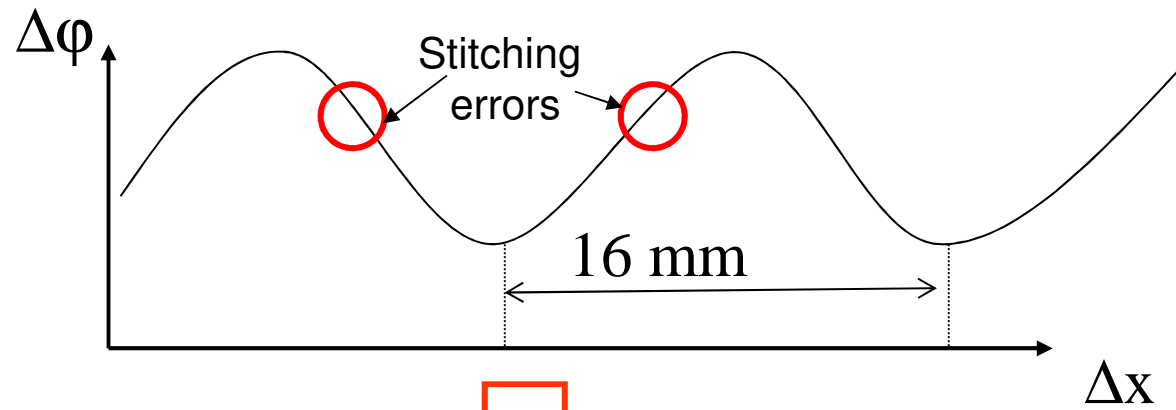
- Linearly chirped grating



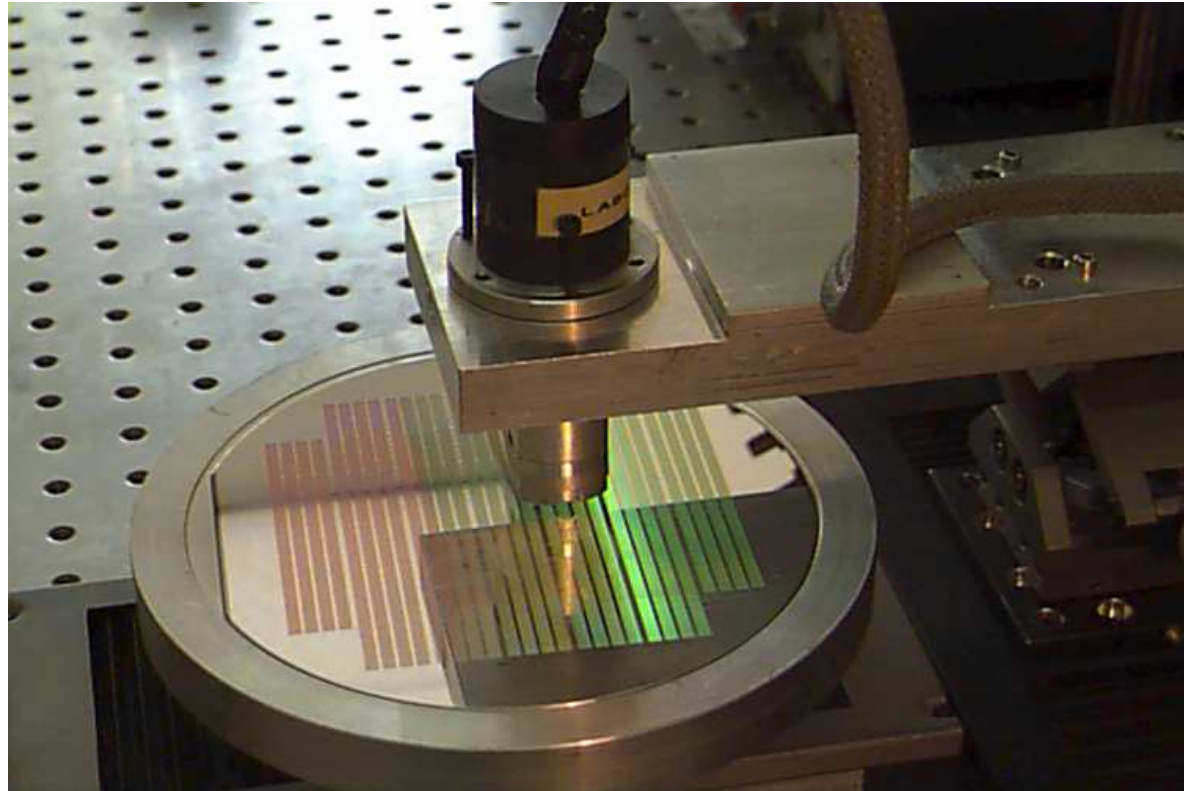
- Ruled grating



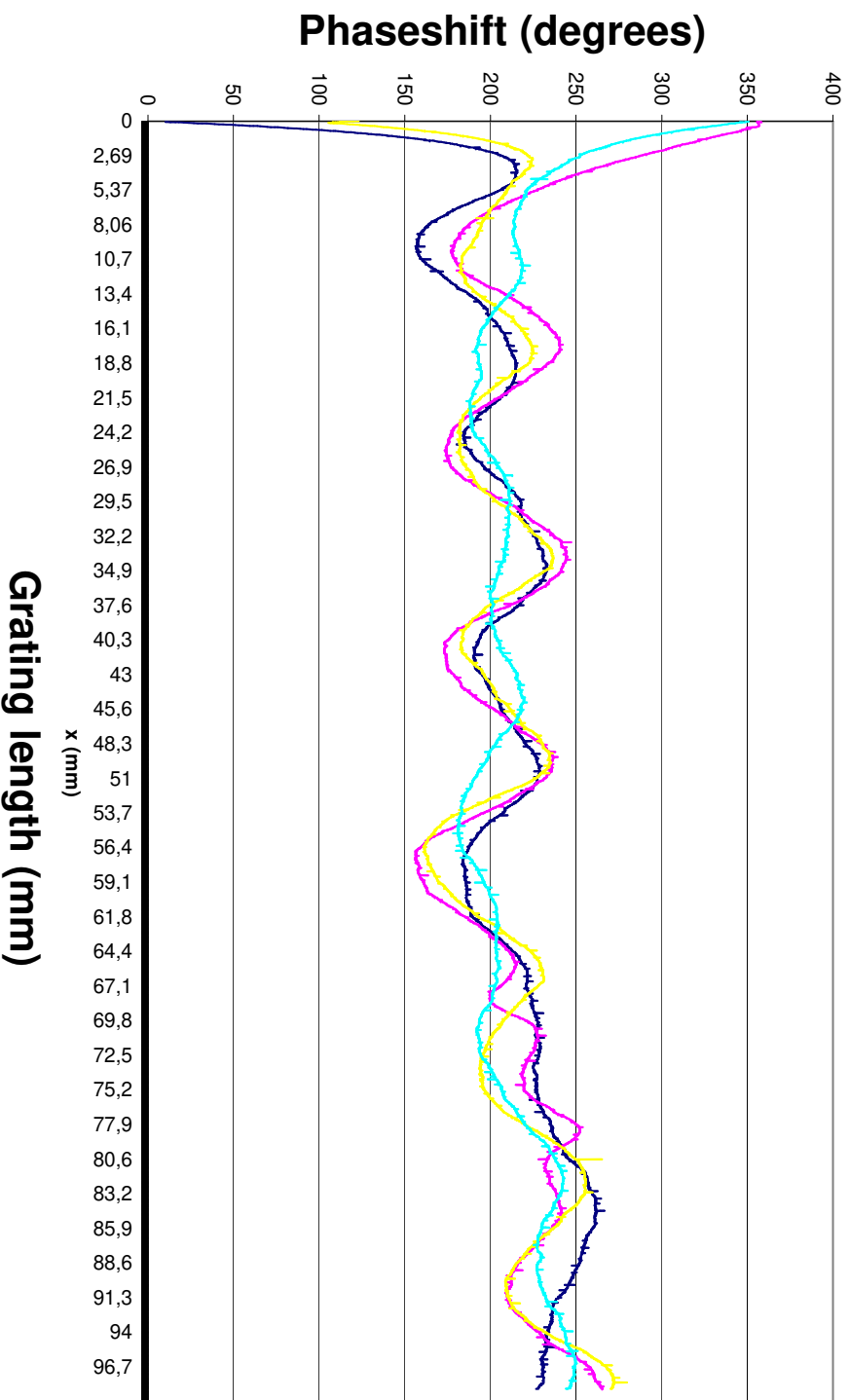
# Step & Repeat grating



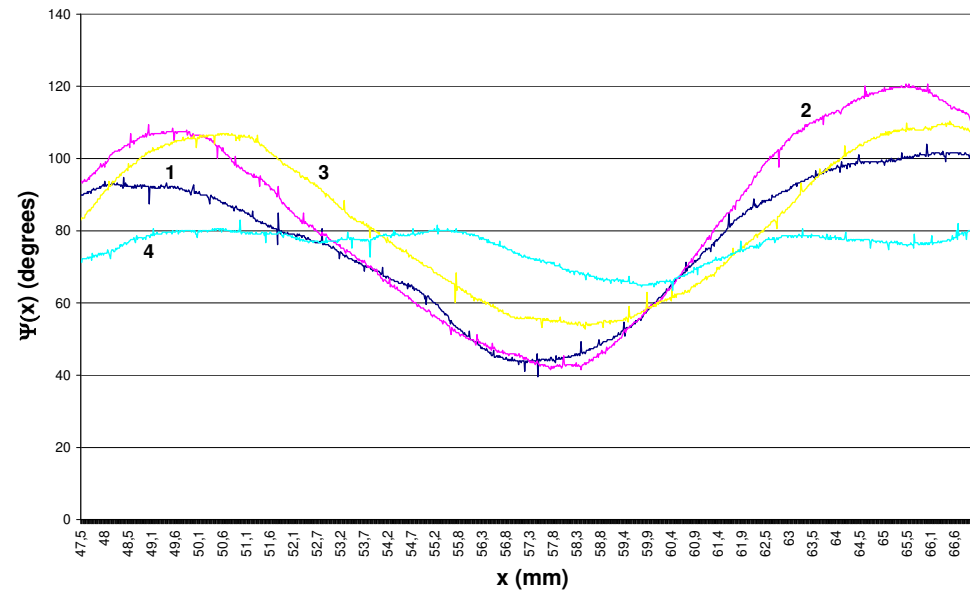
## Scanning of the double read head over a 100 mm grating



# Scanning of the double read head over a 100 mm grating



## Plot of the phaseshift measured on the 4 grating tracks of the same field



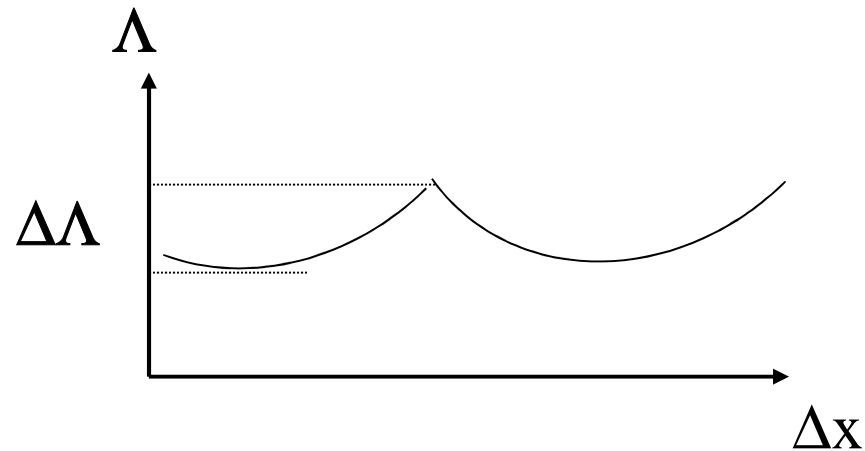
Best fit parameter  $\Delta\Lambda$   
for each grating track

Grating tracks	$\Delta\Lambda$ (nm)
<b>1</b>	<b>0.012</b>
<b>2</b>	<b>0.021</b>
<b>3</b>	<b>0.018</b>
<b>4</b>	<b>0.007</b>

## How good, How bad ?

- **Stitching errors < 10 nm**

- $\Delta\Lambda$



$\Delta\Lambda_{\text{PAS 5500}} < 20 \text{ pm} !$

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# Conclusion

- **Grating scale of displacement sensors**  
Error: maximum of 500 nm per 16 mm  
Can be corrected by choice of nominal  $\Lambda_0$   
100 ppb accuracy possible
  - **Spectroscopy grating**  
«Lambda by 5» grating in the visible  
«Lambda by 15» grating at 1550 nm
  - **Not bad !**
  - **Predistortion ?**  
**=> Perfect gratings !**
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